

## Refine Search

10/786,378

### Search Results -

Terms	Documents
L7 and equation	3

Database:

US Pre-Grant Publication Full-Text Database  
**US Patents Full-Text Database**  
 US OCR Full-Text Database  
 EPO Abstracts Database  
 JPO Abstracts Database  
 Derwent World Patents Index  
 IBM Technical Disclosure Bulletins

Search:

L8

Refine Search

Recall Text

Clear

Interrupt

### Search History

DATE: Saturday, June 26, 2004    [Printable Copy](#)    [Create Case](#)

**Set Name Query**  
side by side

**Hit Count Set Name**  
result set

*DB=USPT; PLUR=YES; OP=ADJ*

<u>L8</u>	L7 and equation	3	<u>L8</u>
<u>L7</u>	L3 and oxidation	6	<u>L7</u>
<u>L6</u>	L5 and plasma	3	<u>L6</u>
<u>L5</u>	L3 and (atomic near2 percent)	4	<u>L5</u>
<u>L4</u>	L3 and (argon adj plasma)	2	<u>L4</u>
<u>L3</u>	L2 and magnesium	18	<u>L3</u>
<u>L2</u>	L1 and (copper adj alloy)	154	<u>L2</u>
<u>L1</u>	(thin adj film) near2 transistor	14127	<u>L1</u>

END OF SEARCH HISTORY

## Hit List

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Search Results - Record(s) 1 through 3 of 3 returned.

☐ 1. Document ID: US 6686661 B1

L8: Entry 1 of 3

File: USPT

Feb 3, 2004

US-PAT-NO: 6686661

DOCUMENT-IDENTIFIER: US 6686661 B1

TITLE: Thin film transistor having a copper alloy wire

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. De
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☐ 2. Document ID: US 6413589 B1

L8: Entry 2 of 3

File: USPT

Jul 2, 2002

US-PAT-NO: 6413589

DOCUMENT-IDENTIFIER: US 6413589 B1

TITLE: Ceramic coating method

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. De
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☐ 3. Document ID: US 5021401 A

L8: Entry 3 of 3

File: USPT

Jun 4, 1991

US-PAT-NO: 5021401

DOCUMENT-IDENTIFIER: US 5021401 A

TITLE: Integrated production of superconductor insulation for chemical vapor deposition of nickel carbonyl

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. De
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Terms

Documents

L7 and equation

3

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Search Results - Record(s) 1 through 6 of 6 returned.

☐ 1. Document ID: US 6743716 B2

L7: Entry 1 of 6

File: USPT

Jun 1, 2004

US-PAT-NO: 6743716

DOCUMENT-IDENTIFIER: US 6743716 B2

TITLE: Structures and methods to enhance copper metallization

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw De
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☐ 2. Document ID: US 6686661 B1

L7: Entry 2 of 6

File: USPT

Feb 3, 2004

US-PAT-NO: 6686661

DOCUMENT-IDENTIFIER: US 6686661 B1

TITLE: Thin film transistor having a copper alloy wire

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw De
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☐ 3. Document ID: US 6420262 B1

L7: Entry 3 of 6

File: USPT

Jul 16, 2002

US-PAT-NO: 6420262

DOCUMENT-IDENTIFIER: US 6420262 B1

TITLE: Structures and methods to enhance copper metallization

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw De
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☐ 4. Document ID: US 6413589 B1

L7: Entry 4 of 6

File: USPT

Jul 2, 2002

US-PAT-NO: 6413589

DOCUMENT-IDENTIFIER: US 6413589 B1

TITLE: Ceramic coating method

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. De
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☐ 5. Document ID: US 5694184 A

L7: Entry 5 of 6

File: USPT

Dec 2, 1997

US-PAT-NO: 5694184

DOCUMENT-IDENTIFIER: US 5694184 A

TITLE: Liquid crystal display device

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. De
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☐ 6. Document ID: US 5021401 A

L7: Entry 6 of 6

File: USPT

Jun 4, 1991

US-PAT-NO: 5021401

DOCUMENT-IDENTIFIER: US 5021401 A

TITLE: Integrated production of superconductor insulation for chemical vapor deposition of nickel carbonyl

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KMC	Draw. De
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Terms	Documents
L3 and oxidation	6

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Search Results - Record(s) 1 through 4 of 4 returned.

☐ 1. Document ID: US 6743716 B2

L5: Entry 1 of 4

File: USPT

Jun 1, 2004

US-PAT-NO: 6743716

DOCUMENT-IDENTIFIER: US 6743716 B2

TITLE: Structures and methods to enhance copper metallization

Full	Title	Citation	Front Page	Classification	Date	Reference	Claims	KMC	Draw De
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☐ 2. Document ID: US 6686661 B1

L5: Entry 2 of 4

File: USPT

Feb 3, 2004

US-PAT-NO: 6686661

DOCUMENT-IDENTIFIER: US 6686661 B1

TITLE: Thin film transistor having a copper alloy wire

Full	Title	Citation	Front Page	Classification	Date	Reference	Claims	KMC	Draw De
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☐ 3. Document ID: US 6541858 B1

L5: Entry 3 of 4

File: USPT

Apr 1, 2003

US-PAT-NO: 6541858

DOCUMENT-IDENTIFIER: US 6541858 B1

TITLE: Interconnect alloy and methods and apparatus using same

Full	Title	Citation	Front Page	Classification	Date	Reference	Claims	KMC	Draw De
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☐ 4. Document ID: US 6420262 B1

L5: Entry 4 of 4

File: USPT

Jul 16, 2002

US-PAT-NO: 6420262

DOCUMENT-IDENTIFIER: US 6420262 B1

TITLE: Structures and methods to enhance copper metallization

Full	Title	Citation	From	Keywords	Classification	Date	Reference			Claims	KWC	Draw. De
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Terms	Documents
L3 and (atomic near2 percent)	4

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Search Results - Record(s) 1 through 2 of 2 returned.

☐ 1. Document ID: US 6,05878 B1

L4: Entry 1 of 2

File: USPT

Dec 17, 2002

US-PAT-NO: 6495878

DOCUMENT-IDENTIFIER: US 6495878 B1

TITLE: Interlayer oxide containing thin films for high dielectric constant application

Full	Title	Citation	Classification	Date	Reference	Claims	KMC	Draw De
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☐ 2. Document ID: US 5,796121 A

L4: Entry 2 of 2

File: USPT

Aug 18, 1998

US-PAT-NO: 5796121

DOCUMENT-IDENTIFIER: US 5796121 A

TITLE: Thin film transparently fabricated on plastic substrates

Full	Title	Citation	Classification	Date	Reference	Claims	KMC	Draw De
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Terms	Documents
L3 and (argon ad) plasma	2

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